

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**OFFICIAL****RECEIVED
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JAN 22 2004

Applicant(s): Yoo, Woo Sik
Assignee: WaferMasters, Inc.
Title: Gas-Assisted Rapid Thermal Processing
Serial No.: 10/005,827 Filing Date: November 8, 2001
Examiner: Trinh, M. Group Art Unit: 2822
Docket No.: M-11914 US

Irvine, California
January 22, 2004

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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Dated: January 5, 2004
Theodore P. Lopez, Reg. No. 44,881

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-1-

Serial No. 10/005,827

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Dear Sir:

Transmitted herewith are the following documents in the above-identified application:

- (1) Certification of Facsimile Transmission;
- (2) This Transmittal Letter (in duplicate); and
- (3) Response to Office Action (4 pages).



No additional fee is required.



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CLAIMS AS AMENDED

	Claims Remaining <u>After Amendment</u>		Highest No. Previously Paid For		Present Extra	Rate	Additional Fee
Total Claims	8	Minus	20	=	0	x \$18.00	\$ 0.00
Independent Claims	2	Minus	4	=	0	x \$84.00	\$ 0.00
<input type="checkbox"/> Fee of _____ for the first filing of one or more multiple dependent claims per application							\$
<input type="checkbox"/> Fee for Request for Extension of Time							\$ 0.00
Total additional fee for this Amendment:							\$ 0.00
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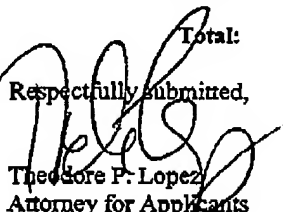
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Adriane Giberson

January 22, 2004

Respectfully submitted,


Theodore P. Lopez
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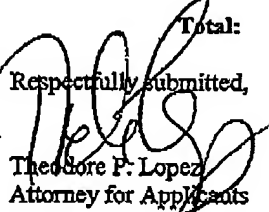
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RESPONSE TO OFFICE ACTION

OFFICIAL

Dear Sir:

In response to the Office Action dated October 22, 2003, Applicants submit the following amendments and remarks.

IN THE CLAIMS

1. (Canceled)

2. (Currently Amended) A system for processing a semiconductor device, the system comprising:

a processing chamber; and

a first plate positioned within said processing chamber and defining a first internal cavity configured to receive a first gas through a first passage into said first internal cavity at a first temperature and to emit said first gas from said first internal cavity at a second temperature through a second passage; and

a second plate disposed adjacent to said first plate, said first plate and said second plate defining a processing area therebetween, ~~wherein~~ said second plate ~~defines~~ defining a second internal cavity configured to receive a second gas through a

-1-

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